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Docket No. 740756-2718

NO. 8723

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:

Mitsuhiro ICHIJO et al.

Application No. 10/804,053

Filed: March 19, 2004

For FILM FORMATION METHOD AND

MANUFACTURING METHOD OF

SEMICONDUCTOR

) Group Art Unit: 2814

) Examiner: Long Pham

) Confirmation No. 7738

) Dated: September 28, 2006

REQUEST FOR RECONSIDERATION

Mail Stop Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450 Sir:

In response to the Office Action mailed June 28, 2006, please consider the remarks in connection with the above-identified application as follows:

Thereby comify that tun the USPTO at 371-271 on the Committee to the USPTO at 371-271 on Thereby Committee the USP

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